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TRANSLATION FROM JAPANESE

- (19) JAPANESE PATENT OFFICE (JP)
- (12) Official Gazette for Unexamined Utility Model Applications (U)
- (11) Unexamined Utility Model No. 58-146346
- (43) Disclosure Date: Oct. 1, 1983

Internal Office

(51) <u>Int. Cl.</u>⁴: <u>Classification Symbols</u>: <u>Registration Nos.</u>:

H01J 37/20 7129-5C

37/18 7129-5C

Request for Examination: Not filed

(Total of 1 page [in original])

- (54) Title of the Invention: Sample exchange device for scanning electron microscope
- (21) Application No.: 57-42991
- (22) Filing Date: Mar. 26, 1982
- (72) Inventor: ISHIMORI Yoshio
- (72) Inventor: SHIBUKI Yoichi
- (71) Applicant: NIPPON DENSHI KK
- (57) Claims

Sample exchange device for scanning electron microscope, [said device] comprising a plurality of sample exchange chambers arranged in communication with a

sample chamber and a vacuum valve; and means for preliminary evacuation of each individual sample exchange chamber, and designed such that while a sample exchange chamber is being subjected to preliminary evacuation in preparation for introduction of a sample into the sample chamber via said sample exchange chamber, another sample may be observed.

Brief Description of the Drawings

The drawing illustrates an embodiment of the invention.

1: lens barrel; 2: sample chamber; 3: stage; 4a, 4b: sample exchange chambers; 5a, 5b, 6a, 6b, 12a, 12b, 13a, 13b, 14, 15, 16, 17, 18: vacuum valves; 7a, 7b: sample exchange rods 11: rotary pumps; 9a, 9b: evacuation lines; 10: diffusion pump; Ha, Hb: sample holders.

公開実用 昭和58一

∯ 日本国特許庁 (JP)

11実用新案出顧公開

2 公開実用新案公報 (U)

昭58-146346

51 Int. Cl.3

类别記号

庁内整理番号

43公開 昭和58年(1983)10月1日

H 01 J 37/20 37-18

7129-5C 7129-5C

審查請求 未請求

(全 頁)

対走査電子顕微鏡等の試料交換装置

株式会社内 72考 案... 者

21天 類 昭57-42991 **洪木洋一**

四出 願 昭57(1982)3月26日 昭島中中神町1418番地日本電子

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